

Inventor: Craig Carpenter et al.

Title: Deposition Methods Utilizing Microwave Excitation, and Deposition Apparatuses

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

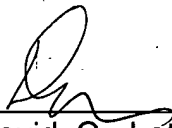
References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (1276 OG 55). No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 10/30/2003

By:


David G. Latwesen, Ph.D.
Reg. No. 38,533

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2434		PRIORITY SERIAL NO. 10/121,320	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Micron Technology, Inc.			
				PRIORITY FILING DATE 4/11/2002		PRIORITY GROUP 1763	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,951,887	9/14/99	MABUCHI et al.			
	AB	6,446,573	9/10/02	HIRAYAMA et al.			
	AC	5,988,104	11/23/99	NAMBU			
	AD	5,788,778	8/4/98	SHANG et al.			
	AE	6,347,602	2/19/2002	GOTO et al.			
	AF	5,645,644	7/8/1997	MABUCHI et al.			
	AG	6,311,638	11/6/2001	ISHII et al.			
	AH	5,545,258	8/13/96	KATAYAMA et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AI						
	AJ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AK						
	AL						
	AM						
	AN						
	AO						
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

EV318283328

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2434		PRIORITY SERIAL NO. 10/121,320	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Micron Technology, Inc.			
				PRIORITY FILING DATE 4/11/2002		PRIORITY GROUP 1763	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,527,908	3/4/2003	KANETSUKI et al.			
	AB	6,158,383	12/12/2000	WATANABE et al.			
	AC	5,134,965	8/4/1992	TOKUDA et al.			
	AD						
	AE						
	AF						
	AG						
	AH						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AI						
	AJ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AK						
	AL						
	AM						
	AN						
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

EV318283328